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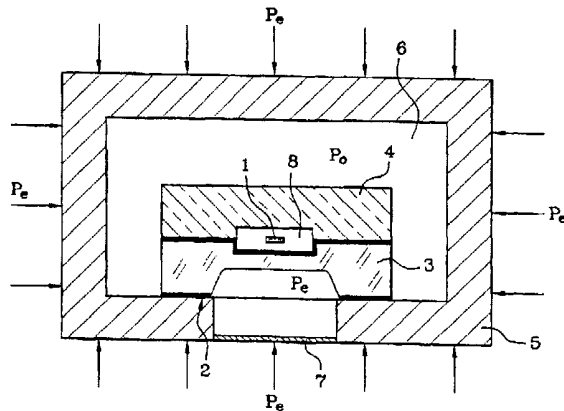
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(54) Abstract Title: **A resonance-type microelectronic pressure sensor that withstands high pressures**

(57) A microelectronic pressure sensor comprises a resonator (23) made on the basis of a crystalline material and secured to the inside of a package (24) made use of a cap (27) and a baseplate (26) for assembling one to the other. The cap (27) and the baseplate (26) are made completely or almost completely out of the same material as the resonator (23), and the pressure (P_e) to be detected is applied all around the package.



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